

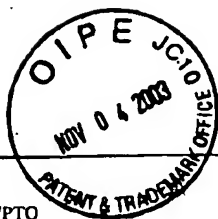


INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)			Complete if Known		
			Application Number	10/616,873	
			Filing Date	July 10, 2003	
			First Named Inventor	Xunming Deng	
			Group Art Unit	2812;Conf. No. 1562	
Sheet	1	of	2	Examiner Name	
				Attorney Docket Number	03108/PHYS00303

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number/Kind Code (if known)			
Ae		US- 5,082,359	01-1992	Kirkpatrick	
		US- 5,397,737	03-14-1995	Mahan et al.	
		US- 5,776,819	07-07-1998	Mahan et al.	
		US- 6,124,186	09-26-2000	Molenbroek et al.	
		US- 6,214,706 B1	04-10-2001	Madan et al.	
		US- 6,251,183 B1	06-26-2001	Iwancizko et al.	
Ae		US- 6,427,622	08-2002	Madan et al.	
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Country Code-Number-Kind Code (if known)				

Examiner Signature		Date Considered	1/22/04
-----------------------	--	--------------------	---------



Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/616,873
				Filing Date	July 10, 2003
				First Named Inventor	Xunming Deng
				Group Art Unit	2812;Conf. No. 1562
				Examiner Name	
Sheet	2	of	2	Attorney Docket Number	03108/PHYS00303

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	2 ²
Ac		H. Povolny, S. Han, X.B., Xiang and X. Deng/Hot-Wire Deposition of c-Si and a-Si Using Different Gas Excitations By A Coiled Filament/Abstract submitted to 19 th International Conference Amorphous and Microcrystalline Semiconductors Science and Technology (ICAMS19) Acropolis Center, Nice, France, 27-31 August 2001	
		Xunming Deng/Construction of a novel hot-wire deposition system employing a coiled hot filament/Disclosed at "Amorphous Silicon Team Meeting" for NREL/DOE (Nat'l Renewable Energy Laboratory/Dept. of Energy) in August 2000.	
		S. Yu, E. Gulari, and J. Kanicki/Center for Display Technology and Manufacturing, University of Michigan, Ann Arbor, Michigan 48109/Selective deposition of polycrystalline silicon thin films at low temperature by hot-wire chemical vapor deposition/May 1996.	
Ac		Mitsuru Ichikawa, Jun Takeshita, Akira Yamada and Makoto Konagai/Dept. of Electrical and Electronic Engineering, Tokyo, Japan/Jpn. J. Appl. Phys. Vol 38 (1999) pp. L24-L26, Part 2, No. 1A/B, 15 January 1999, ©1999 Publication Board, Japanese Journal of Applied Physics/January 1999.	

Examiner Signature		Date Considered	1/22/04
-----------------------	--	--------------------	---------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² Applicant is to place a check mark here if English language Translation is attached.